On The Bumpy Road Towards 3D Photonic Metamaterials

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Outline

Metamaterials as effective media Hitherto existing realizations of 3D metamaterials • Fabricational approaches for the NIR • Our fabricational approach Recent results Current projects Conclusions and outlook

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General definition:

Metamaterials are **artificially fabricated effective materials** that provide material-light interactions which are not accessible by naturally available substances.

Some popular special cases:

u Magnetic photonic metamaterials ($\mu \neq 1$) Negative-index materials $(\mu, \varepsilon < 0)$ plus some other assumptions) Electric Cloaks (anisotropic variation of ε from 1 to 0) Enhanced non-linear optical response (high values for $\chi^{(2)}, \chi^{(3)}$) Chiral metamaterials (enhanced optical activity)

Relevant equations:

1. Maxwell's equ. rot $\vec{E} = -\vec{B}$ div $\vec{D} = \rho$ rot $\vec{H} = \vec{j} + \vec{D}$ div $\vec{B} = 0$

2. Material equ. $\vec{D} = \mathcal{E}_0(\vec{E} + \vec{P})$ $\vec{B} = \mu_0(\vec{H} + \vec{M})$

Simplify material equations: **1.** $\vec{j}_{av}, \rho_{av} = 0$ **2.** Describe $\vec{P}(\vec{E},\vec{H})$ and $\vec{M}(\vec{E},\vec{H})$ by $\vec{\varepsilon}$, $\vec{\mu}$, $\vec{\xi}$ and $\vec{\zeta}$ $\rightarrow \vec{P} = (\vec{\varepsilon} - 1)\vec{E} + \vec{\xi}\vec{H}$; $\vec{M} = (\vec{\mu} - 1)\vec{H} + \vec{\zeta}\vec{E}$ **But**: Only possible if we assume an eff. material! A (wavelength) >> a (unit cell) $d_{\text{propdir}} > \lambda$ (wavelength)

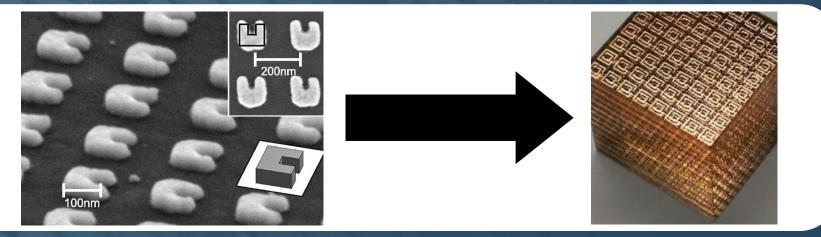
Need for effective materials

Motivation to fabricate 3D metamaterials

→ Is the formalism of bulk materials also applicable to "flat" structures?

ANSWER: Sometimes!

Usually: Simple effective material models of electrically thin layers (height $< \lambda$) are limited in their physical meaning!



E. Seanz *et al.*, J. Appl. Phys. **101**, 114910 (2007) M.W. Klein *et al.*, Opt. Lett. **31**, 1259 (2006)

Let's assume that we have an eff. medium:

Isotropic media: • ε , $\mu \in \mathbb{C}$ • ξ , $\zeta = 0$

Anisotropic media: • ε , μ are tensors • ξ , ζ = 0

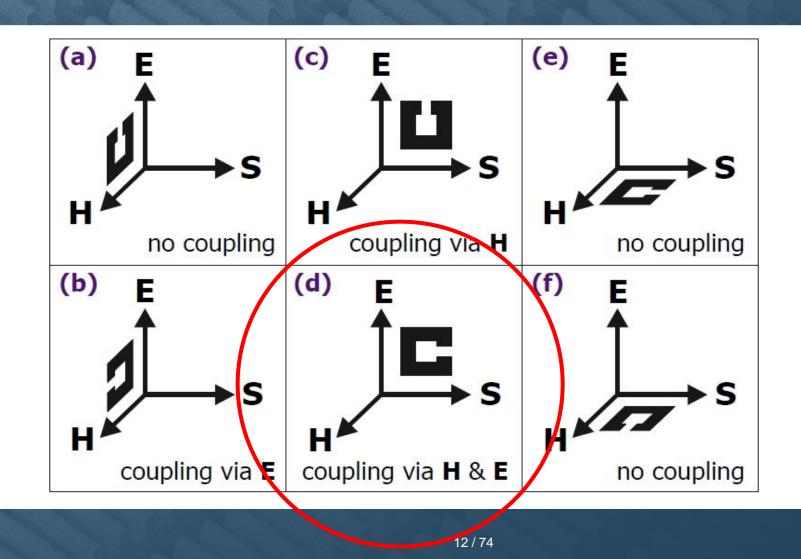
Bi-isotropic media: • ε , $\mu \in \mathbb{C}$ • ξ , $\zeta \in \mathbb{C}$ Bi-anisotropic media: • ε , μ are tensors • ξ , ζ are tensors

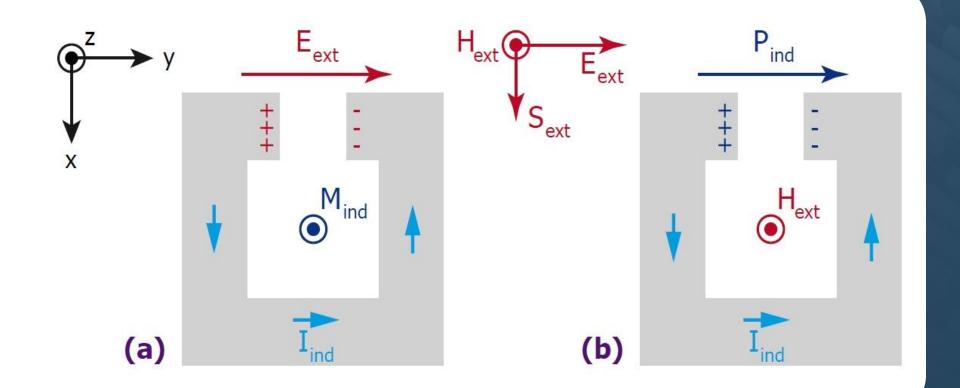
Who cares?

Investigators of ...

■ Metallic sub-wavelength structures → effective material with $\mu \neq 1$

 ■ Non-symmetric atoms along propagation direction
 → cross-coupling





C. Kriegler, diploma thesis (2008)

Physical description:

 $\vec{D} = \varepsilon_0 \vec{\varepsilon} \vec{E} + c_0^{-1} \vec{\xi} \vec{H}$ $\vec{B} = c_0^{-1} \vec{\zeta} \vec{E} + \mu_0 \vec{\mu} \vec{H}$

 Reciprocal medium (exchange of currents and fields is possible / NO Faraday effect)

Geometry as shown
 before

$$\vec{\varepsilon} = \begin{pmatrix} \varepsilon_x & 0 & 0 \\ 0 & \varepsilon_y & 0 \\ 0 & 0 & 1 \end{pmatrix}, \quad \vec{\mu} = \begin{pmatrix} 1 & 0 & 0 \\ 0 & 1 & 0 \\ 0 & 0 & \mu_z \end{pmatrix}$$
$$\vec{\xi} = \begin{pmatrix} 0 & 0 & 0 \\ 0 & 0 & -i\xi \\ 0 & 0 & 0 \end{pmatrix}, \quad \vec{\zeta} = \begin{pmatrix} 0 & 0 & 0 \\ 0 & 0 & 0 \\ 0 & i\xi & 0 \end{pmatrix}$$

X. Chen *et al.*, Phys. Rev. E **71**, 046610 (2005) R. Marqués *et al.*, Phys. Rev. B **65**, 144440 (2002)

Long story short:

 $D_{y} = \varepsilon_{0}\varepsilon_{y}E_{y} - i\xi c_{0}^{-1}H_{z} \quad ; \quad B_{z} = \mu_{0}\mu_{z}H_{z} + i\xi c_{0}^{-1}E_{y}$

After calculating the dispersion relation with an harmonic ansatz (as "usual"), we finally derive:

$$n = \sqrt{\varepsilon_y \mu_z - \xi^2}$$
; $z_{\pm} \equiv \frac{Z_{\pm}}{Z_{\text{vac}}} = \frac{\mu_z}{\pm n - i\xi}$ direction dependent

How can we determine *n* and z_{\pm} ?

 ■ Effective material parameters are not observable.
 ■ Easiest way: measure *T* and *R*_±
 ■ Problem: Lossy material → ε, μ, ξ ∈ Ω (6 unknown variables)

Solution: Simulate $t, r_{\pm} \in \mathbb{C}$ and compare with experimental data

A.3. RETRIEVAL OF THE EFFECTIVE PARAMETERS

We already noticed that Z_+ is the impedance of the bianisotropic medium in the (+)-direction and $Z_$ is the opposite of the impedance in the (-)-direction. This accounts for (A.18). Yet, it is not clear a priori whether z_+ and z_- defined in (A.17) fulfil the condition (A.18). We decided to define z_\pm as in (A.17) because it turned out to fulfil (A.18) in all the cases we studied, but the condition (A.18) should be tested in every case.

To find the refractive index, we can rewrite (A.13) and (A.14) as:

$$\begin{array}{rcl} t_+ & = & \displaystyle \frac{\mathrm{e}^{\mathrm{in}k_0 d}}{\left(1-\frac{z_-}{z_t}\right)} \left(\left(1-\frac{z_-}{z_t}\right)+r_+\left(1+\frac{z_-}{z_t}\right) \right) \\ t_+ & = & \displaystyle \frac{\mathrm{e}^{-\mathrm{in}k_0 d}}{\left(1-\frac{z_+}{z_t}\right)} \left(\left(1-\frac{z_+}{z_t}\right)+r_+\left(1+\frac{z_+}{z_t}\right) \right) \end{array}$$

Finally, we get an implicit expression for the refractive index

$$\cos nk_0 d = \frac{t_+}{2} \left(\frac{1 - \frac{z_-}{z_t}}{\left(1 - \frac{z_-}{z_t}\right) + r_+ \left(1 + \frac{z_-}{z_t}\right)} + \frac{1 - \frac{z_+}{z_t}}{\left(1 - \frac{z_+}{z_t}\right) + r_+ \left(1 + \frac{z_+}{z_t}\right)} \right).$$
(A.19)

A.3 Retrieval of the Effective Parameters

(A.19) has an infinity of solutions for n due to the inverse cosine. We proceed as in the symmetric case to choose the correct branch [Enk05].

Once z_{\pm} and n are calculated, we deduce ϵ , μ and ξ from (A.19) and (A.17):

$$\xi = \ln\left(\frac{z_- + z_+}{z_- - z_+}\right)$$

$$\epsilon = \frac{n + \imath\xi}{z_+}$$

$$\mu = z_+ (n - \imath\xi)$$

A.3. RETRIEVAL OF THE EFFECTIVE PARAMETERS

$$z_{\pm} = (-b \mp \sqrt{b^2 - 4ac})/(2a)$$
, with

 $a = t_{air}t_{sub} - (1 - r_{air}) (1 - r_{sub}),$

$$b = (z_{air} - z_{sub}) (t_{air} t_{sub} + 1 - r_{air} r_{sub}) + (z_{air} + z_{sub}) (r_{air} - r_{sub}),$$

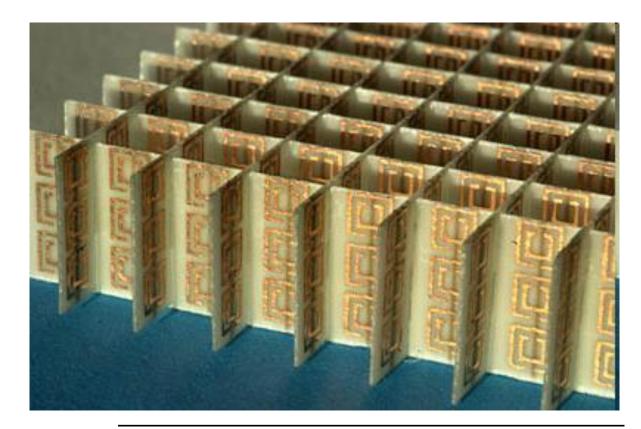
 $c = z_{\text{air}} z_{\text{sub}} \left(-t_{\text{air}} t_{\text{sub}} + (1+r_{\text{air}}) \left(1+r_{\text{sub}} \right) \right),$

$$\cos(nk_0d) = \frac{t_{\rm air}}{2} \left[\frac{\left(1 - \frac{z_-}{z_{\rm sub}}\right)}{\left(1 - \frac{z_-}{z_{\rm air}}\right) + r_{\rm air}\left(1 + \frac{z_-}{z_{\rm air}}\right)} + \frac{\left(1 - \frac{z_+}{z_{\rm sub}}\right)}{\left(1 - \frac{z_+}{z_{\rm air}}\right) + r_{\rm air}\left(1 + \frac{z_+}{z_{\rm air}}\right)} \right]$$

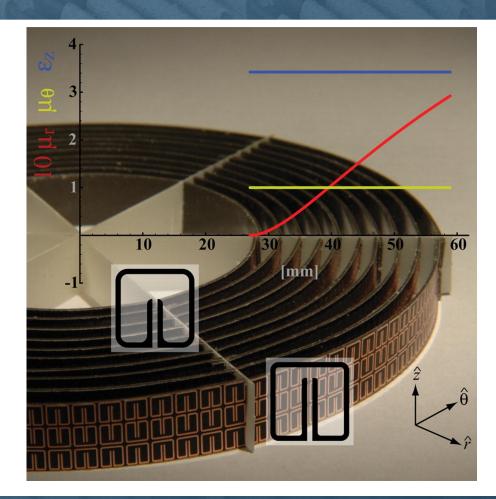
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"Experimental verification of a negative index of refraction"



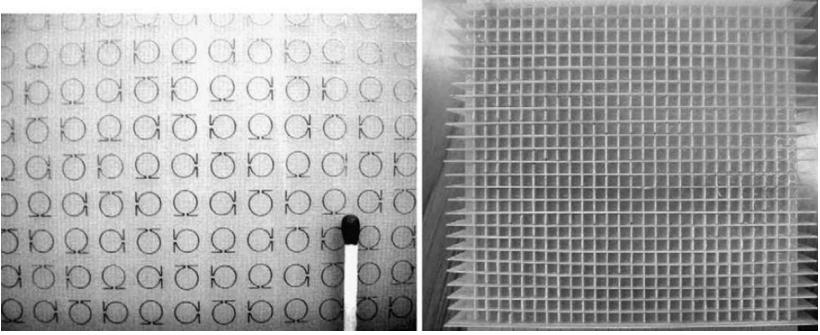
R.A. Shelby et al., Science 292, 77 (2001)



"3D metamaterial electromagnetic cloak at microwave frequencies"

> D. Schurig *et al.*, Science **314**, 977 (2006)

"Isotropic metamaterial electromagnetic lens"



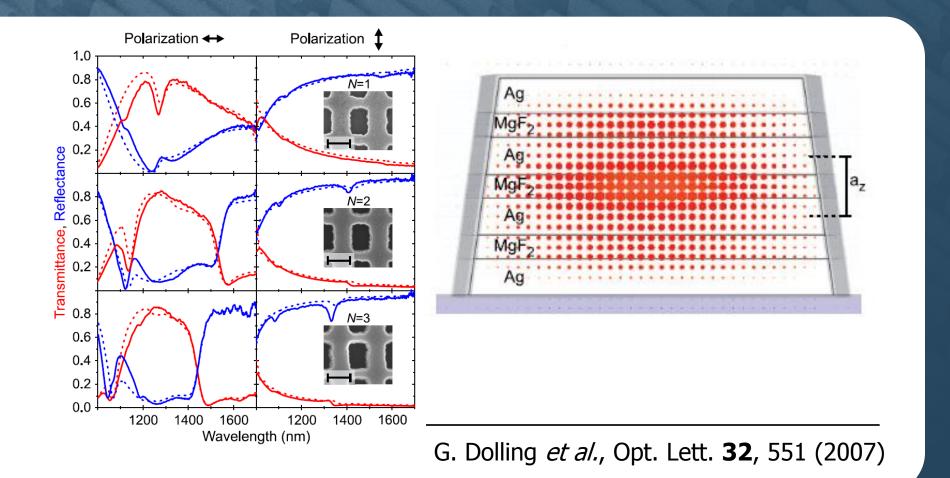
E. Verney et al., Phys. Lett. A 331, 244 (2004)

A real 3D meta<u>material</u> for the NIR or VIS optical range (regarding $\lambda < d_{propdir}$) has not been reported, yet!

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Fabricational approaches for the NIR: Simple stacking (layer-by-layer)



Fabricational approaches for the NIR: Simple stacking (layer-by-layer)

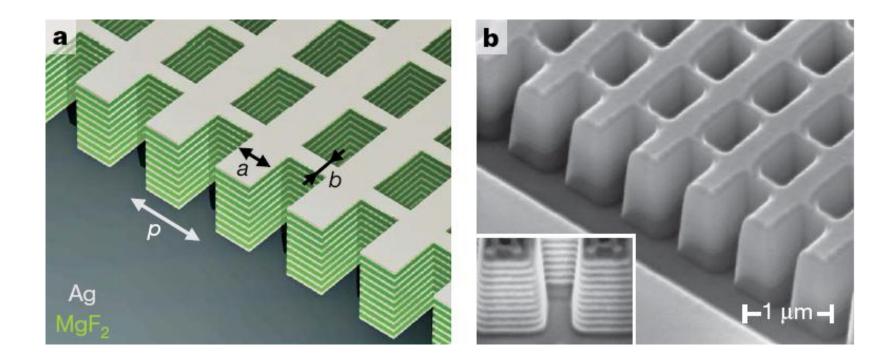
PROs:

No special fabrication techniques neededStructuring needs just one process step

CONs:

Stacking of more than 4 functional layers not possible due to lift-off problems
 Tapering

Fabricational approaches for the NIR: FIB-milling from the solid



J. Valentine *et al.*, Nature **455**, 376 (2008)

Fabricational approaches for the NIR: FIB-milling from the solid

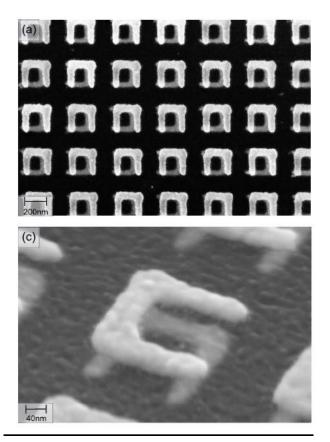
PROs:

No special fabrication techniques neededStructuring needs just one process step

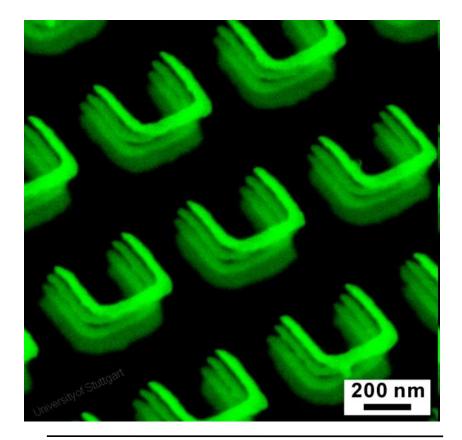
CONs:

Tapering (max. 10 functional layers)
Ga contamination due to FIB-milling
Restriction to planar structure designs

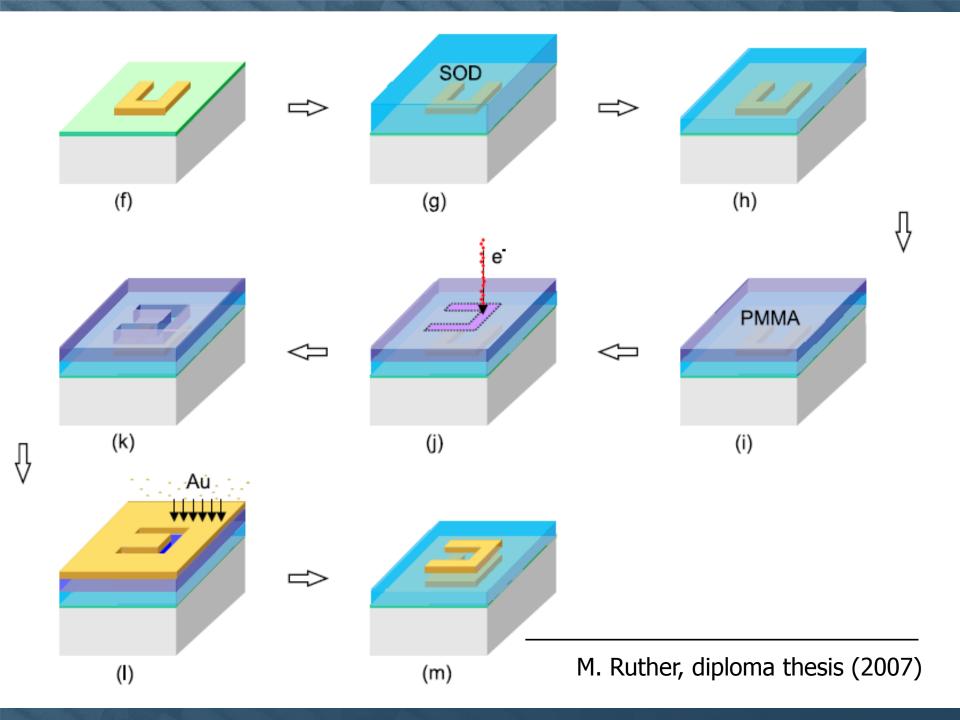
Fabricational approaches for the NIR: Planarization method (layer-by-layer)



M. Ruther, diploma thesis (2007)



N. Liu et al., Nature Mater. 7, 31 (2008)



Fabricational approaches for the NIR: Planarization method (layer-by-layer)

PROs:

Spin-on-dielectric (IC2-200[®] – Polysiloxane compound) acts as a capacitance
 Arbitrarily scalable

CONs:

 ■ Very time-consuming (many process steps) → approx. 1 day per unit cell
 ■ Re-alignment before e-beam lithography
 ■ Restriction to planar structure designs

Fabricational approaches for the NIR: Intermediate conclusions

What do all these approaches have in common?

■ Restriction to planar (2D) designs
 → unsuitable for isotropic structures
 → very hard to achieve heights d > λ

u Time-consuming (serial processing)

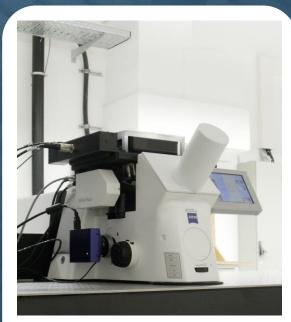
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Our fabrication approach Overview

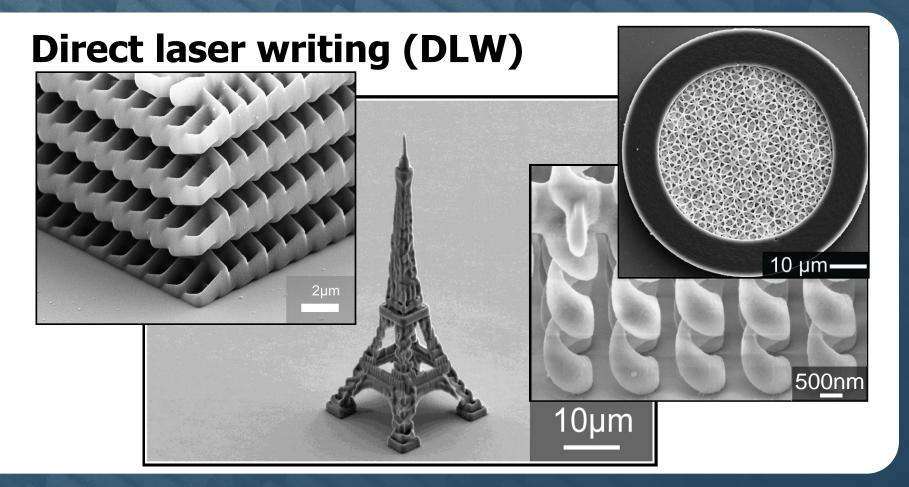
- 1. Fabrication of dielectric template by direct laser writing
- 2. Protection layer by SiO_2 or TiO_2 atomic layer deposition

3. Isotropic metallization





Our fabrication approach Step 1: Direct laser writing



M. Thiel, diploma thesis A. Ledermann *et al.*, Nature Mater. **5**, 942 (2006)

Our fabrication approach Step 1: Direct laser writing

PROs:

- Feature sizes down to 100 nm (depends mainly on photo resist)
- **u** Sample volume: 300 μm x 300 μm x 80 μm
- **u** Easy fabrication (CAD support, WYSIWYHTG)
- Chemically and mechanically robust

CONs:

- Always connected structures
- Sensitive to high temperatures (> 150 °C)
- **u** Proximity effect
- **u** Aspect ratio of voxel (2.8:1 for SU-8)



Our fabrication approach Step 2: Protection layer

Protection coating before metallization

Deformation of template @ 160°C

□ SiO₂ PLD Process:
 • Alternating pulses of H₂O and SiCl₄:
 SiCl₄ + H₂O → SiO₂ + HCl

 Purging with N₂ in between
 Process @ room temperature and atmospheric pressure



E. J. Ehrlich *et al.*, Appl. Phys. Lett. **58**, 2675 (1991)

Our fabrication approach Step 2: Protection layer

Protection coating before metallization

II TiO₂ ALD Process:

• Alternating pulses of H₂O and TiCl₄:

 $TiCl_4 + H_2O \rightarrow TiO_2 + HCI$

Purging with N₂ in between
Process @ 110°C

Self-saturazing
 (1 monolayer per cycle)



http://www.cambridgenanotech.com

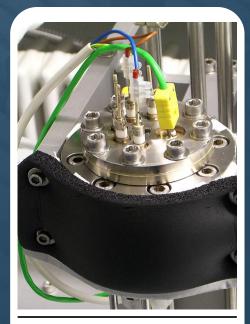
Sputtering processes not suitable (only 2D)

Useful 3D metallization processes:

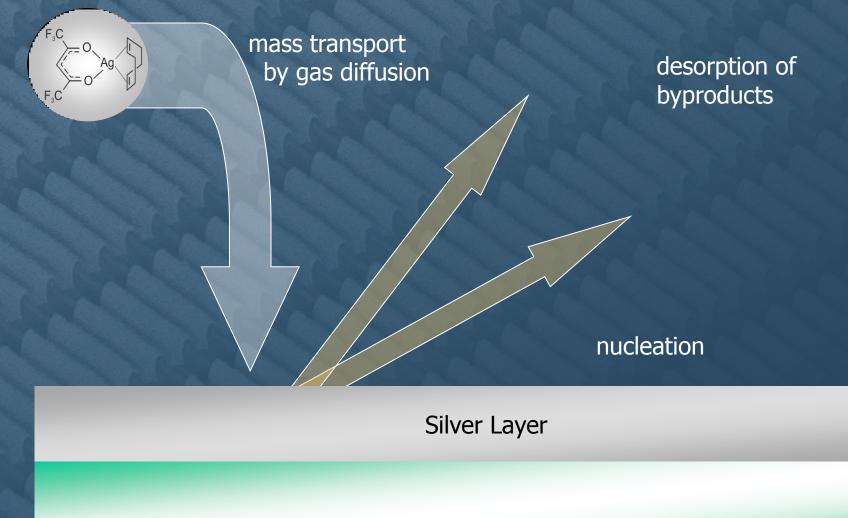
• Electrochemical deposition (ECD) e.g., Na₃[O₃S-Au⁽¹⁾-SO₃] (aqueous solution)

• Atomic layer deposition (ALD) e.g., $[Cu({}^{s}Bu-amd)]_2 + NH_3 \rightarrow Cu_3N + lig.$ $2 Cu_3N + 3 H_2 \rightarrow 6 Cu + 2 NH_3$

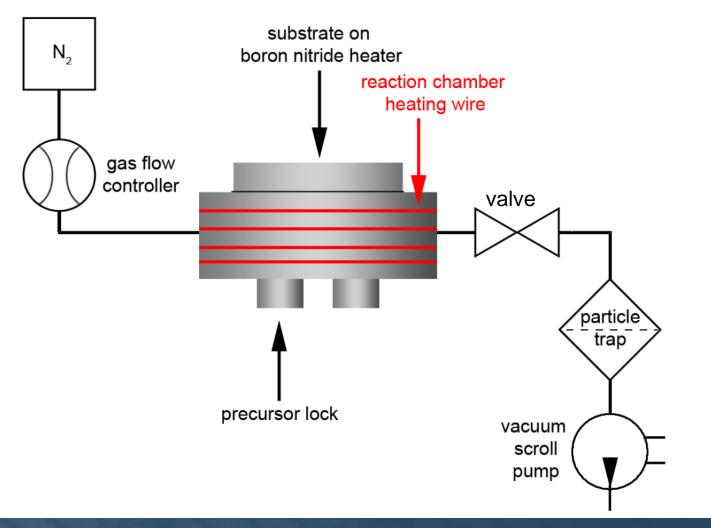
• Chemical vapor deposition (CVD) e.g., (COD)(hfac)Ag⁽¹⁾

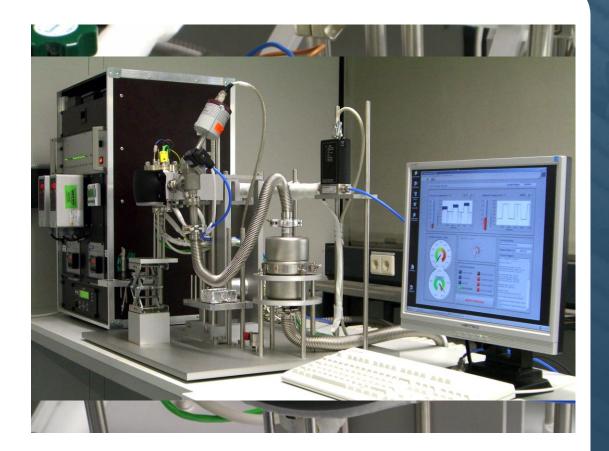


Me, Mysetficitistell, unpublished



E. Eisenbraun *et al.*, J. Vac. Sci. Technol. B **19**, 585 (2001)





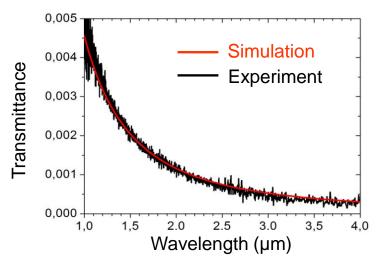
Custom design Ľ Complete Ľ1 automation • reproducable • long-time deposition Several running modes possible • dynamic • static • pulsed

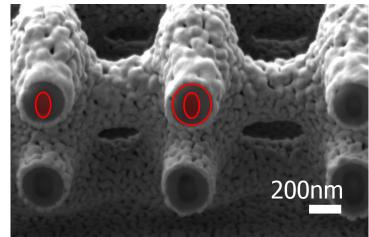
u PROs:

- Connected films (no particle plasmons)
 Pure silver coating
 Drude model fits well
 Isotropic coating of 3
- Isotropic coating of 3D templates

u CONs:

- Whole surface is metallized (even the substrate!)
- Deep trenches and small holes cause problems

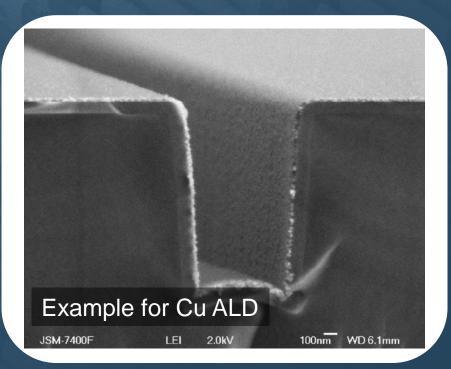


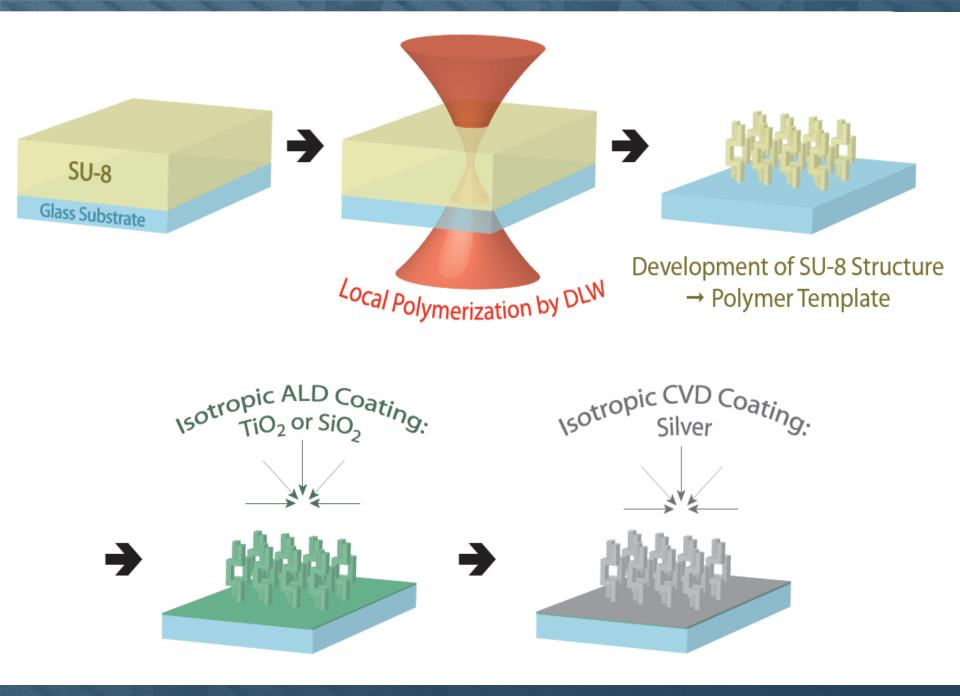


Solution for metallization of substrate:
 Lift-off process with soluable photo resist

 Metallization of deep trenches and high filling fractions:
 Switch to ALD processes

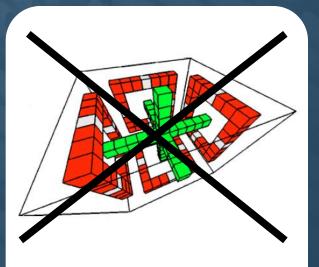
Niskanen *et al.*, J. Elec. Chem. Soc. **152**, G25 (2005)





Our fabrication approach Boundary conditions

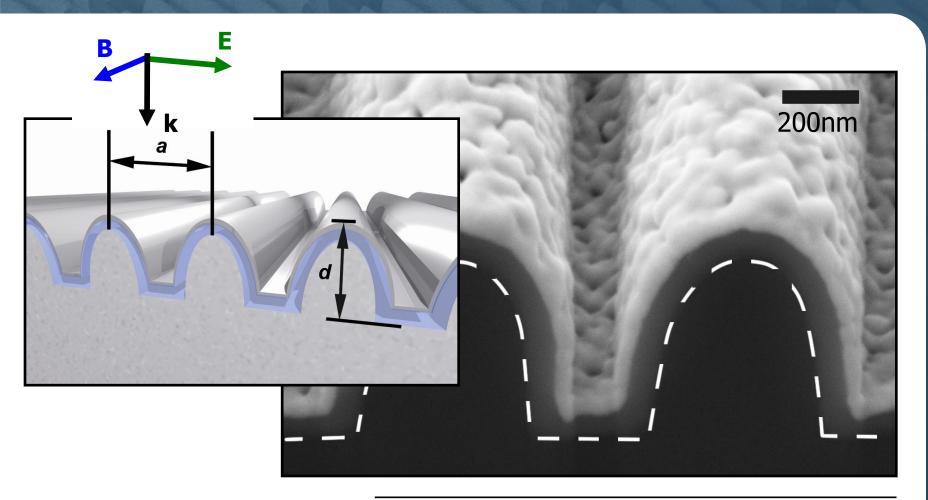
- Connected template structure (no "flying" features)
- Whole surface is metallized (no locally defined coatings)
- Minimum periodicity defined by direct laser writing
 → suitable for near-IR



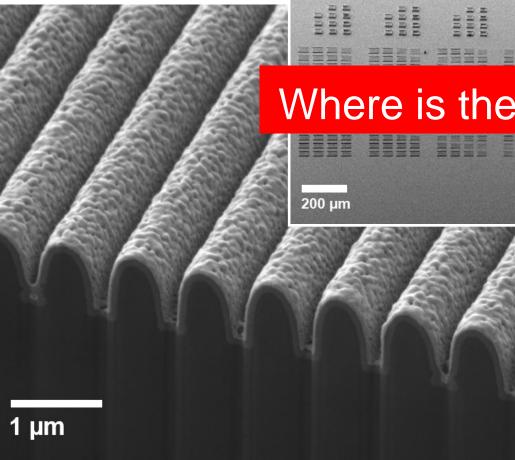
T. Koschny *et al.*, PRB **71**, 121103 (2005)

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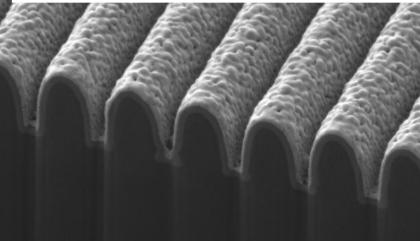
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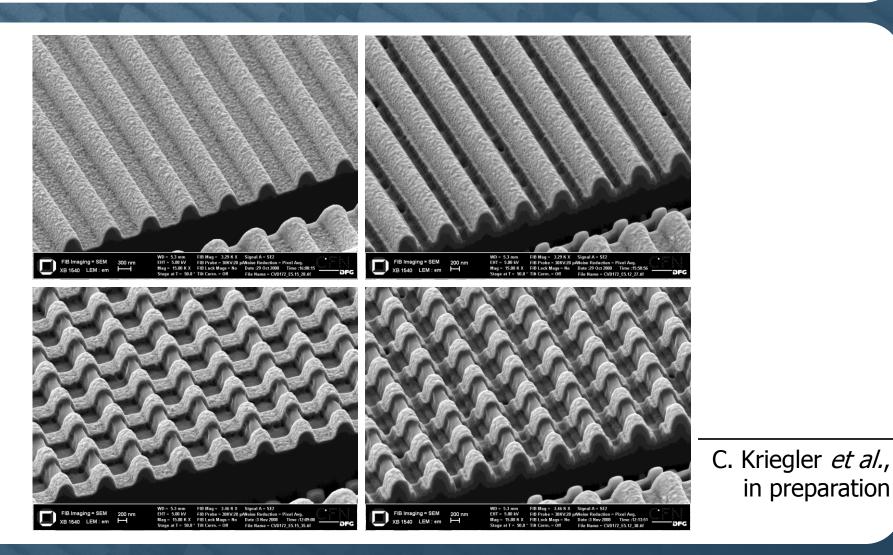


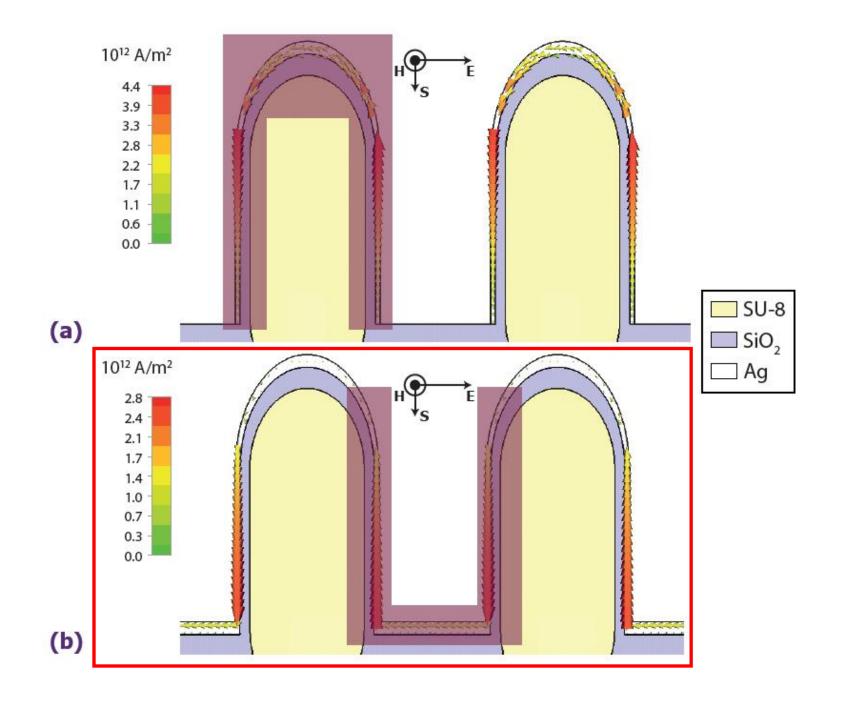
M.S. Rill et al., Nature Mater. 7, 543 (2008)

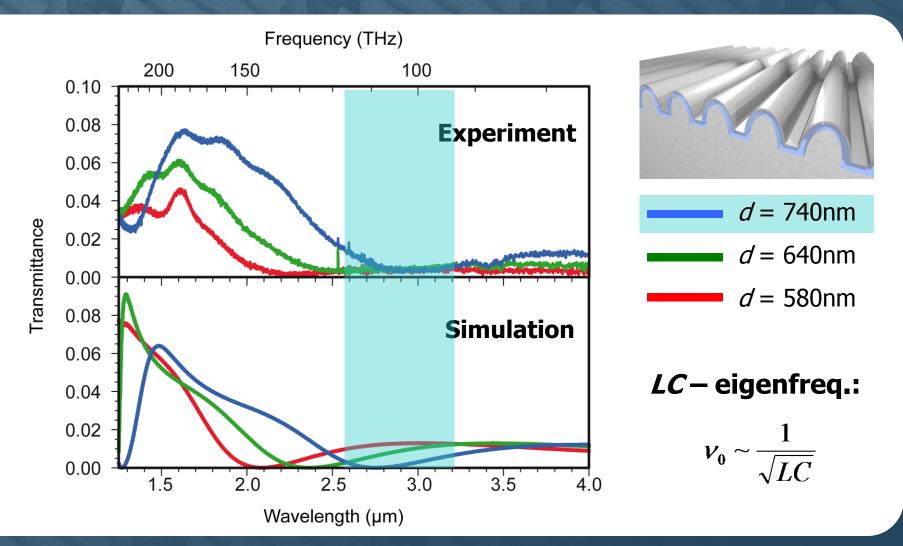


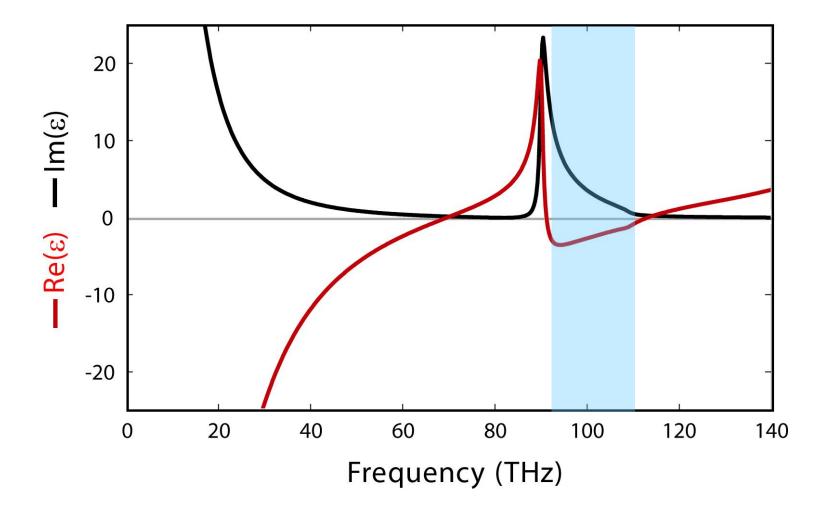
Where is the magnetic atom?

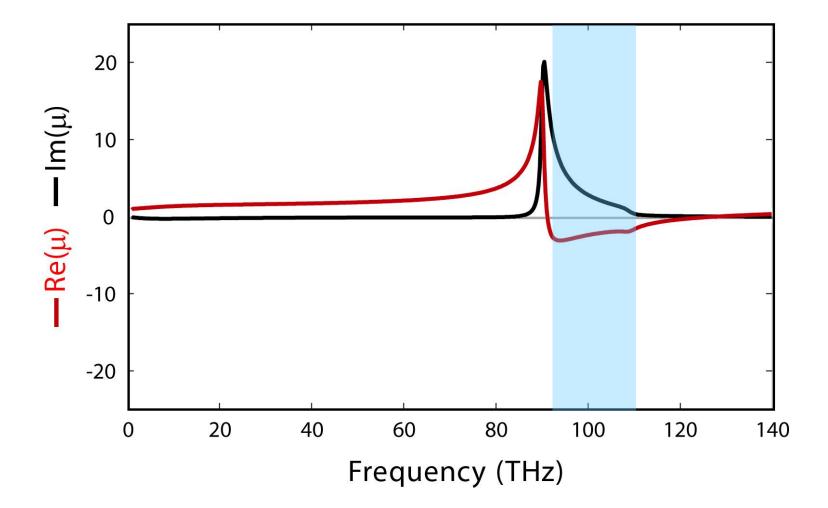


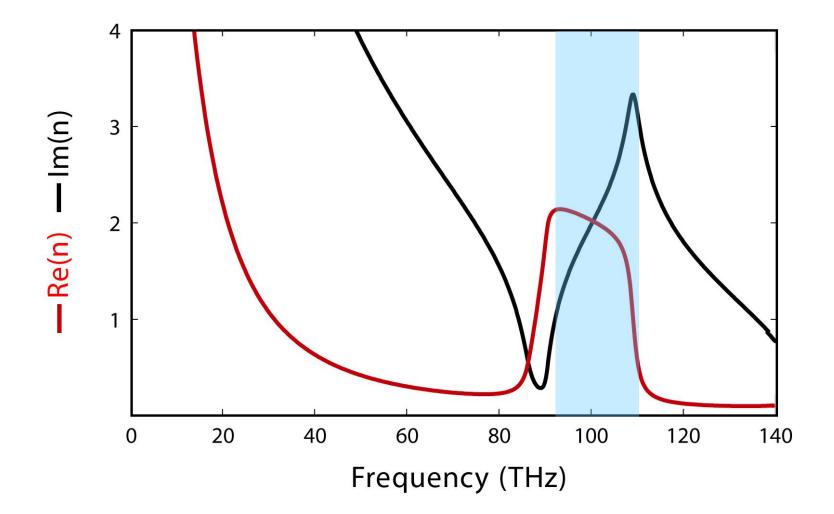


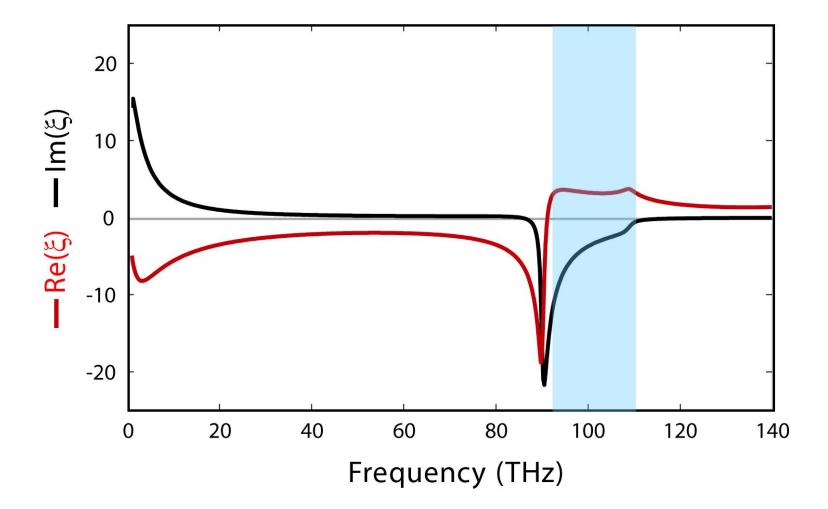








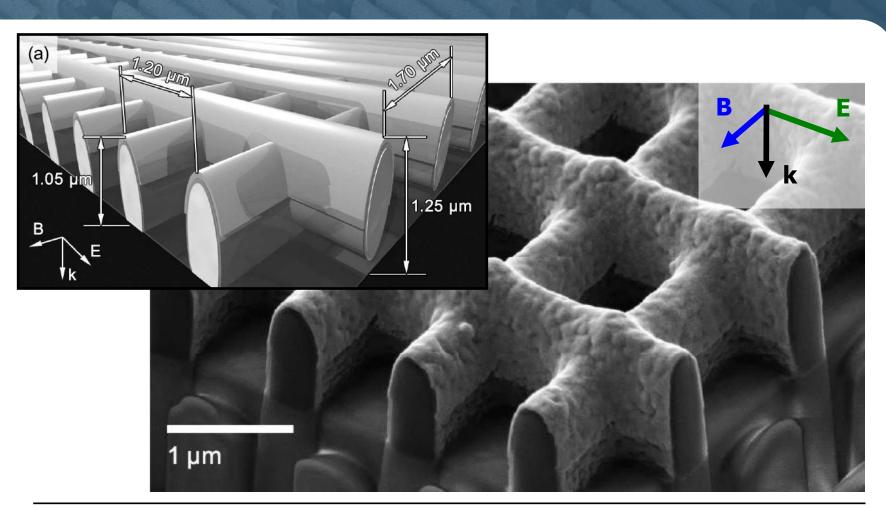




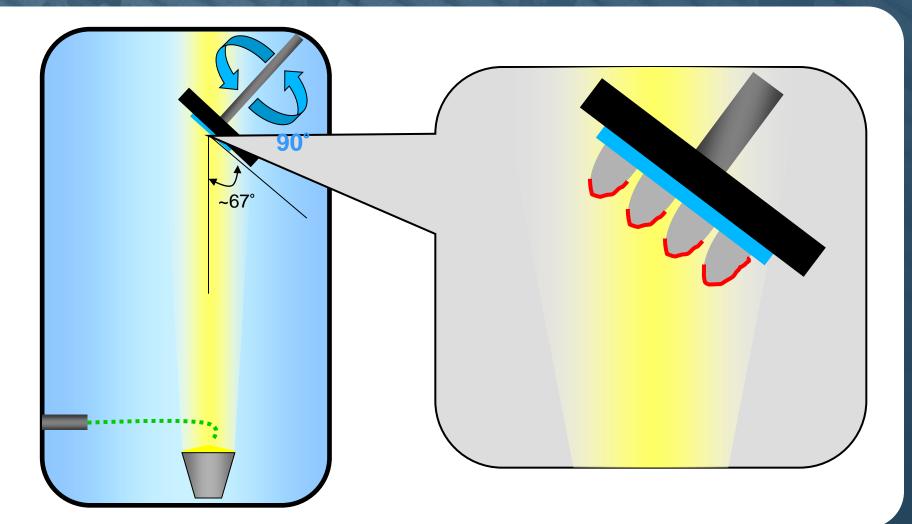
Recent results

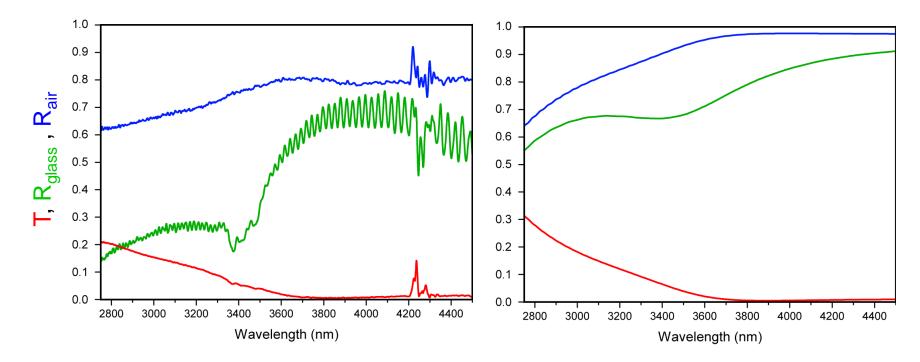
Considering these results could bring us to the question:

"Is bi-anisotropy a killer for negative refractive indices?"



M.S. Rill *et al.*, arXiv:**0809**.2207v1

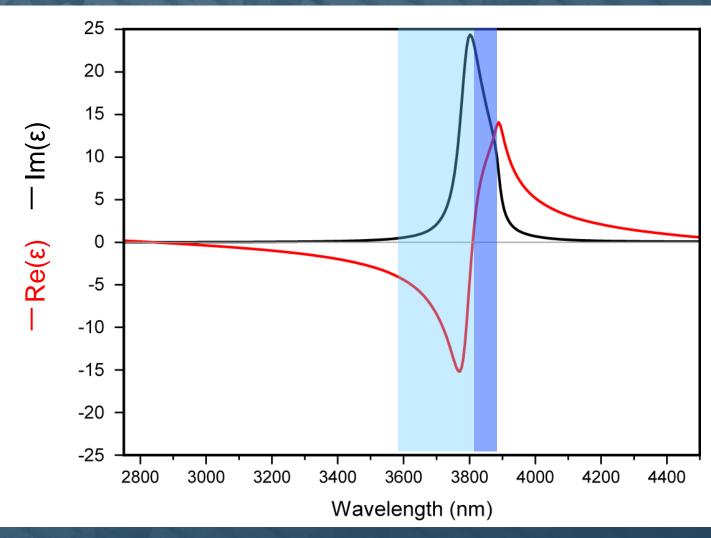


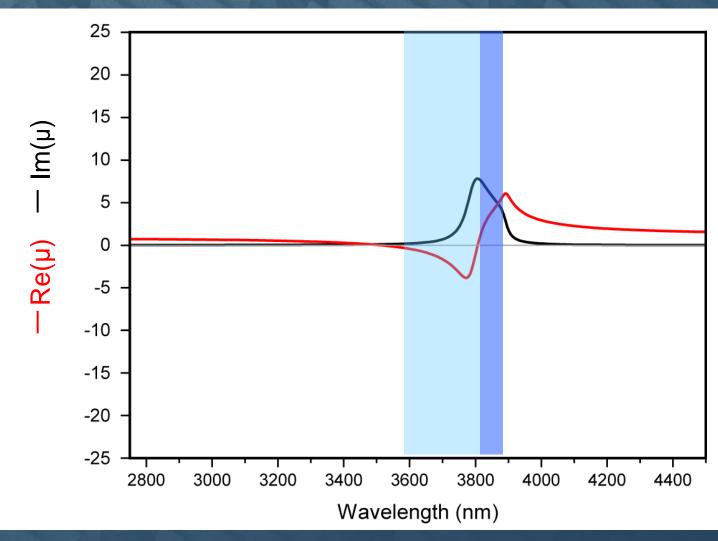


Experiment

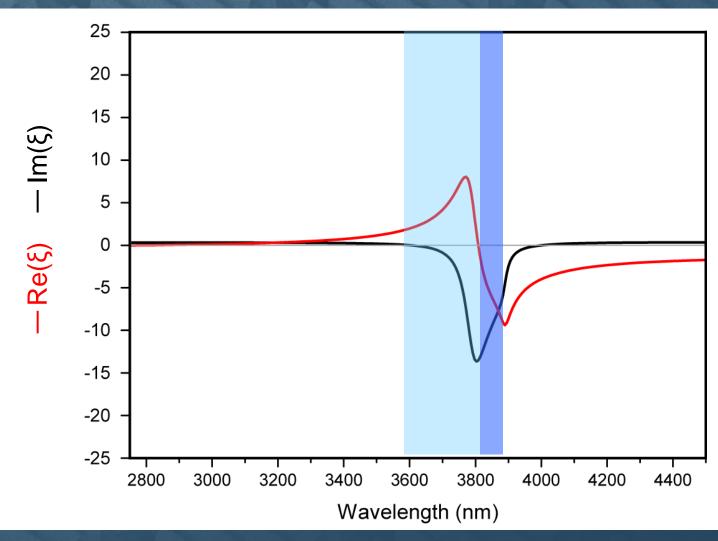
(fringes are due to Fabry-Pérot resonances of the glass substrate)

Theory (calculations performed with CST Microwave Studio)

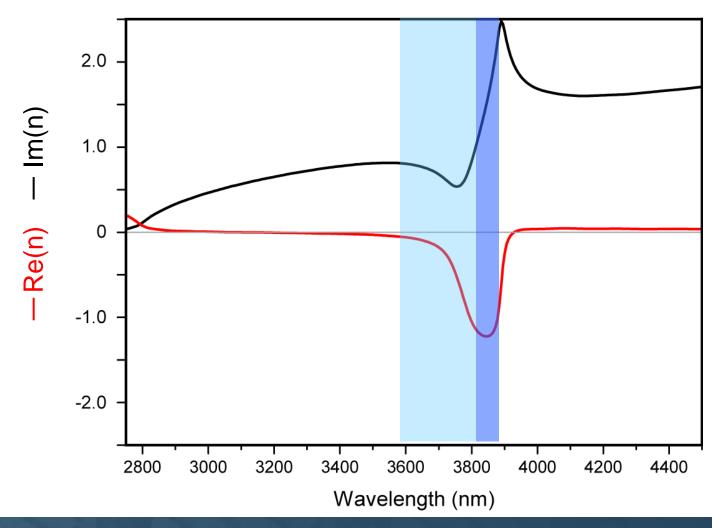




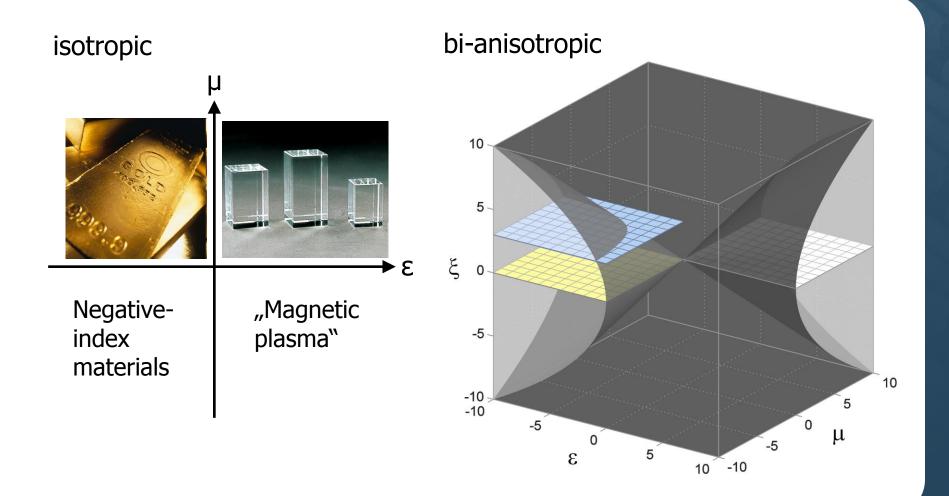
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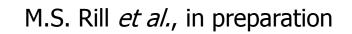


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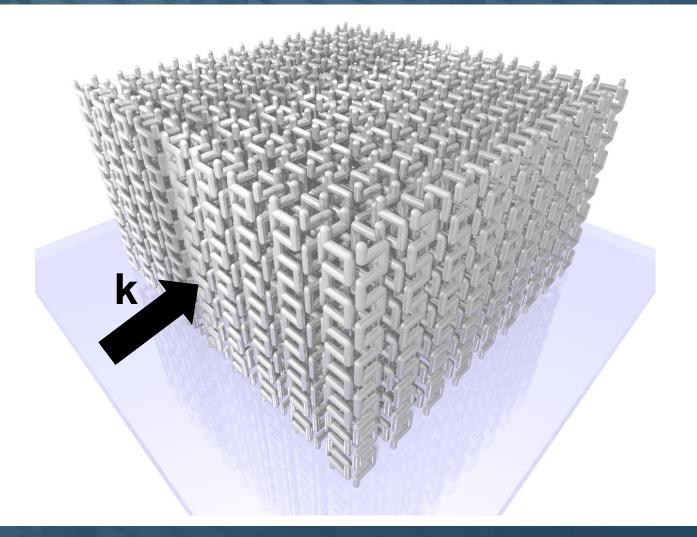
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Current projects 2D isotropic metamaterial

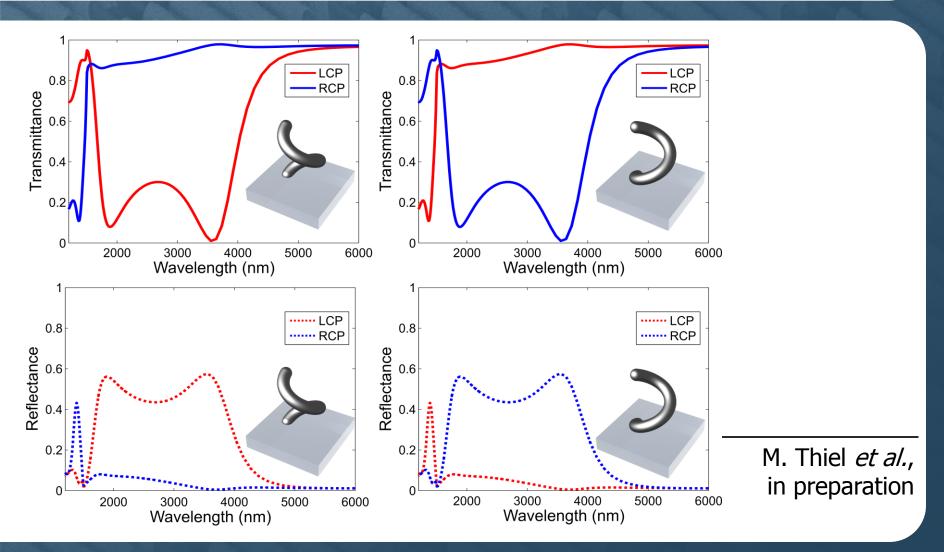
Based on idea of **D. Güney** (Soukoulis group): D.Ö. Güney *et al.*, arXiv:**0807**.4560



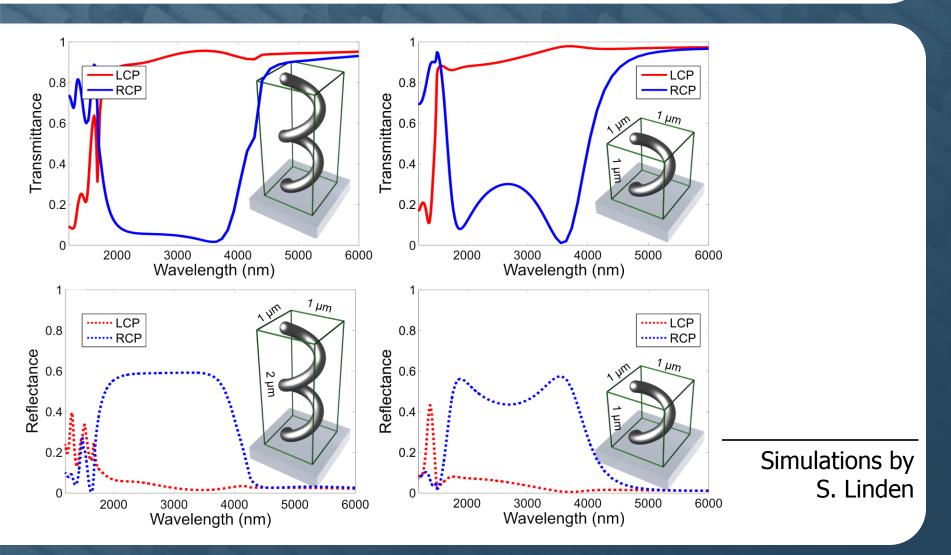
Current projects 2D isotropic metamaterial



Current projects Chiral 3D metamaterials



Current projects Chiral 3D metamaterials



Conclusions

■ Theory to describe even complicated structures
 (→ bi-anisotropy)
 BUT: Structure has to be an effective material!

 ■ Technique which is suitable to fabricate 3D metamaterials for NIR optical range
 (→ We have not fabricated it, yet!)

Found promising design which can be fabricated by our proposed method

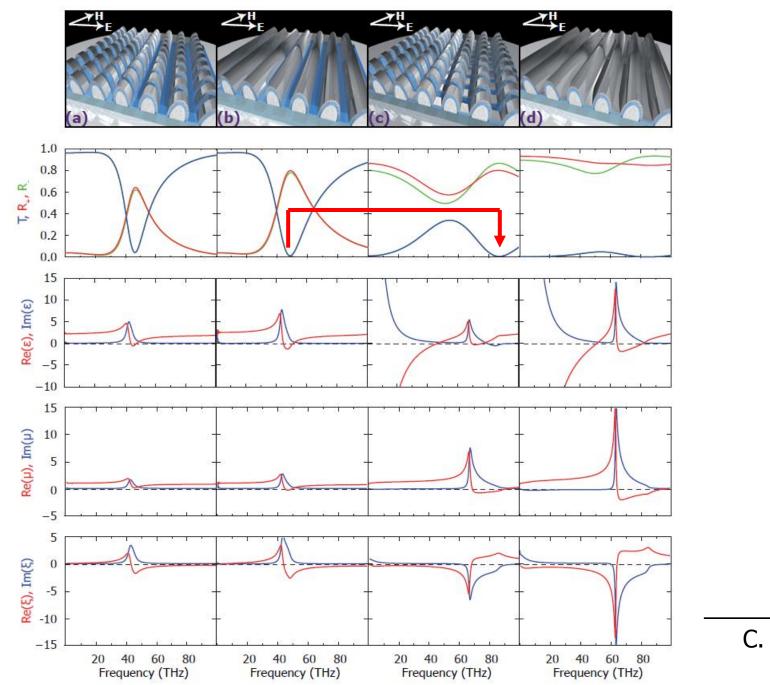
Thanks for your attention!

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C. Kriegler *et al.*, in preparation